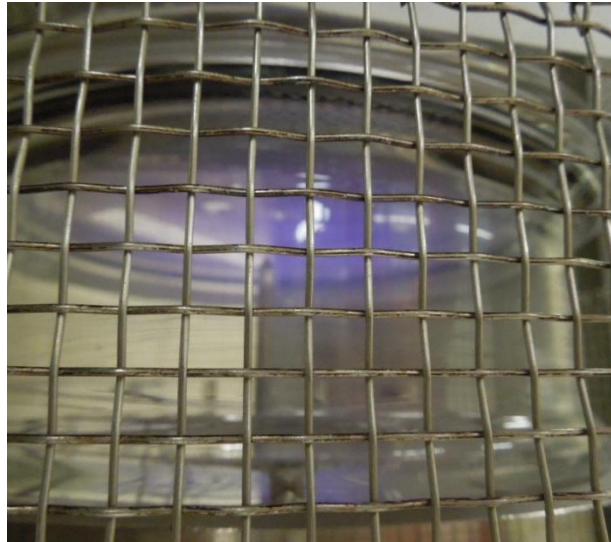


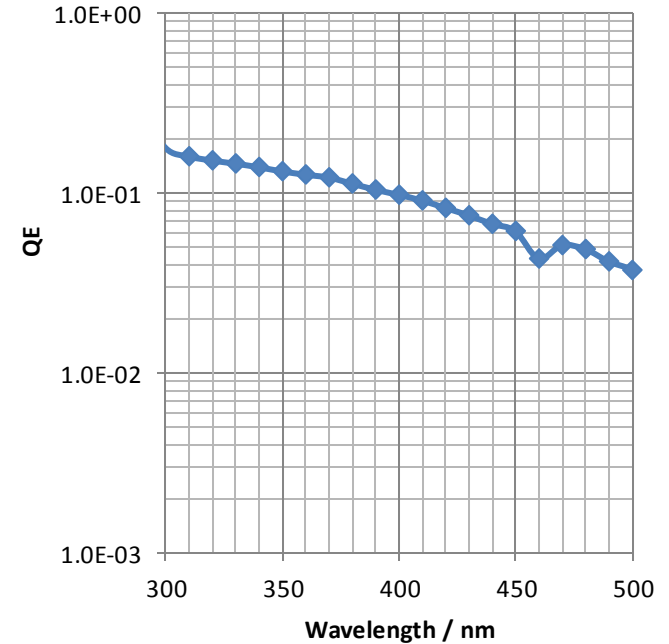
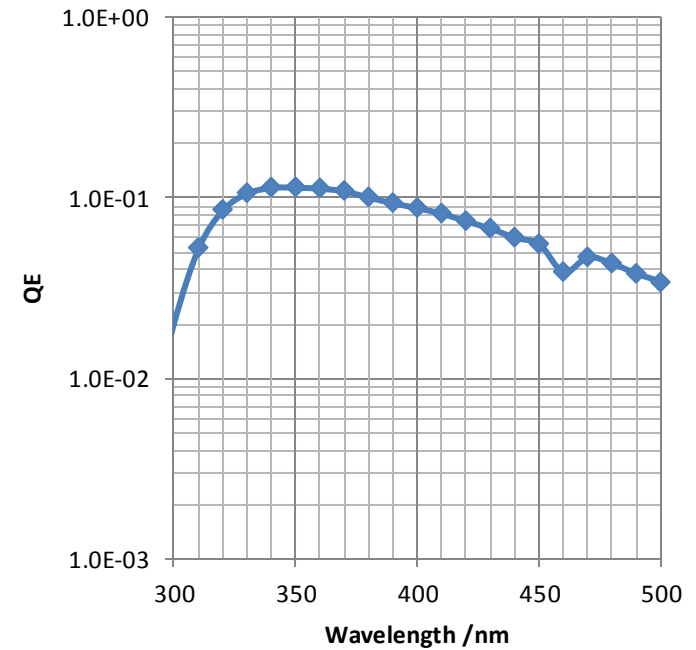
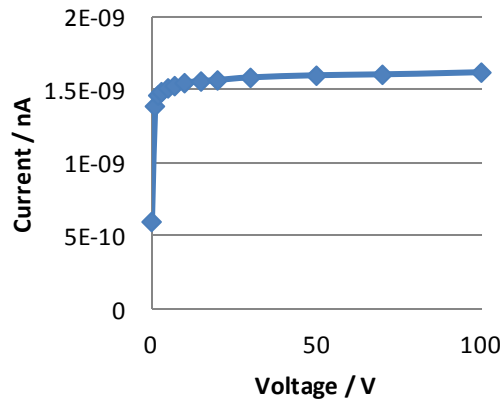
# Chalice cathode deposition #6

Chalice cathode #6 used 6 K and 4 Cs dispensers.  
Sb layer is between Chalice #4 and Chalice #5.

0.3 torr oxygen was used during first plasma,  
oxygen plasma can be seen clearly.

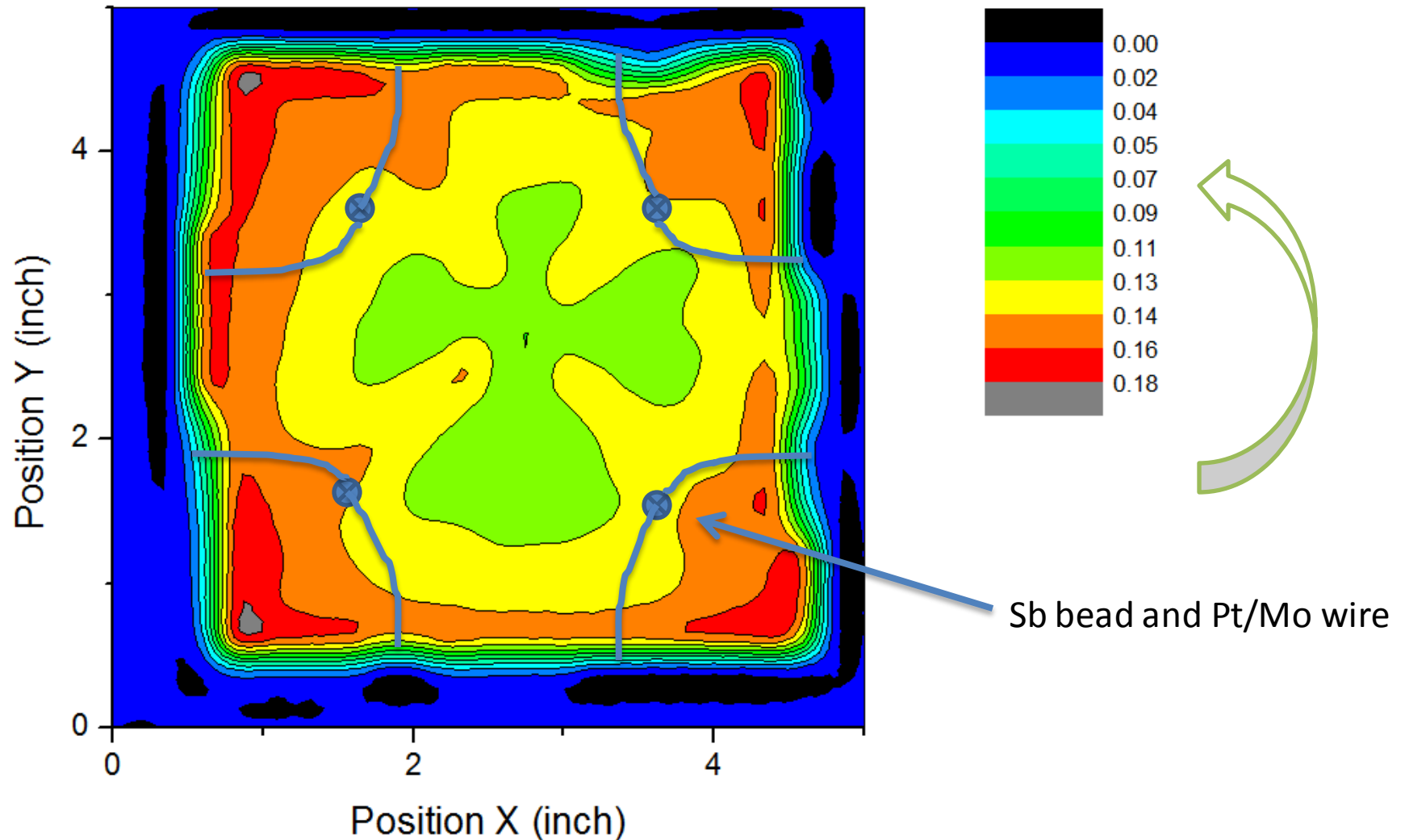


I-V



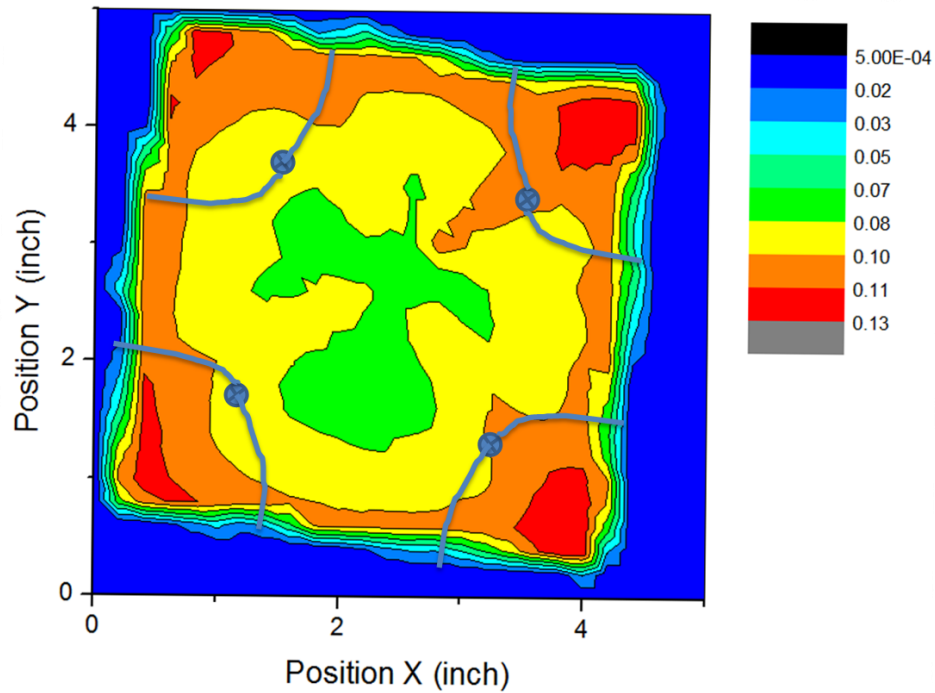
# Chalice cathode deposition #6 Map

The QE mapping is obtained at 350 nm wavelength, scan step size: 0.2 inch

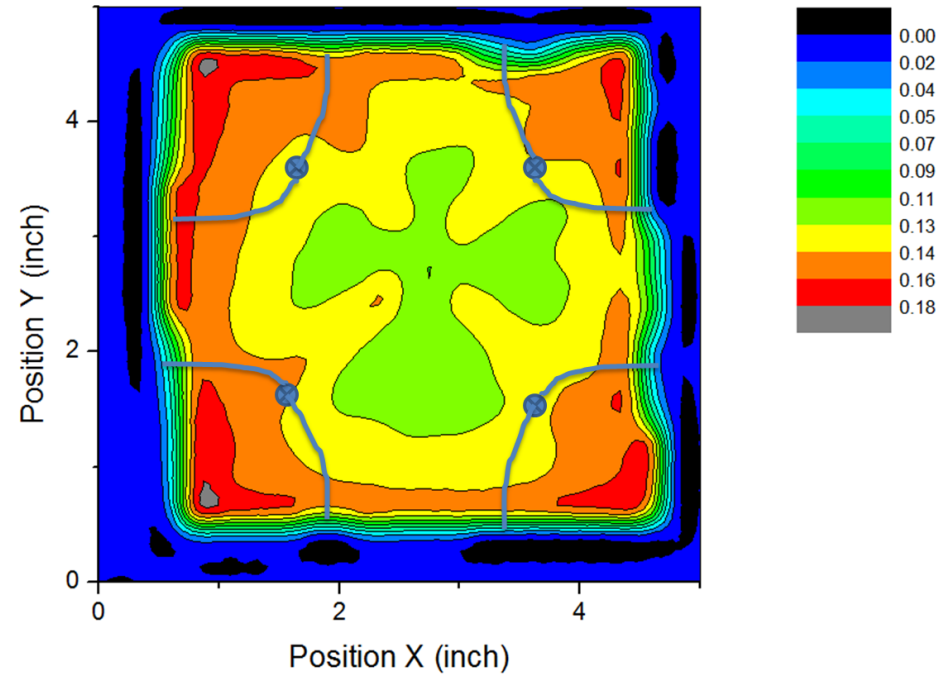


QE between 8% at center and 18% at corners.

Chalice 5 QE mapping



Chalice 6 QE mapping



1. Chalice 5 and Chalice 6 QE mappings are very similar. Due to Sb deposition?  
Or plasma shape?

# Further test for Chalice 6

1. Baking at 100C for 2 hrs, try the re-cesiation process.
2. Make a mechanism arm to scan Sb transmission/reflection data, relate QE value to Sb thickness.
3. Plasma components (resister/core) are arrived, assemble the unit
4. For the next deposition, better to use new mask, so we can get more information about QE vs Sb thickness.